

U.S. Department of Commerce, Patent and Trademark Office	Serial No.: 10/027,882
	Filing Date: 12/21/01
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventors: Vlad J. Novotny
"DEEP-WELL LITHOGRAPHY PROCESS FOR FORMING MICRO-ELECTRO-MECHANICAL STRUCTURES"	Group Art Unit: Unknown 1765
	Examiner Name: Unknown S. Ahmed
	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
AA						
AB						

Foreign Patent Documents

							Translation
	Document Number	Date	Country	Class	Subclass	Yes	No
AC							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

SA	AD	D.J. Bishop Presentation, "Silicon Micromachines for Lightwave Networks: Can Little Machines Make it Big?" Lucent Technologies, Bell Labs Innovations. 83 pages. February 1999.
	AE	
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	AH	
	AI	

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Examiner Shamim Ahmed

Date Considered 7/10/03

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"	Group Art Unit: Unknown
	Examiner Name: Unknown
Express Mail Receipt No.: EK916849783US	Attorney Docket No.: AO-001-2D

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
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SA	AE	6,283,601 B1	09/04/01	Hagelin et al.	359	871	

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SA	AG	"ROUTING PACKETS WITH LIGHT," Daniel J. Blumenthal. Scientific American, pages 96-99. January 2001.						
SA	AH	"Construction and performance of a 576x576 single-stage OXC," Herzel Laor. LEOS, San Francisco, California, 3 pages. November 8, 1999.						
NO Date SA	AI	"Application of micro- and nanotechnologies for the fabrication of optical devices," Wolfgang Ehrfeld and Hans-Dieter Bauer. SPIE Vol. 3276, page 2 and pages 4-14.						
SA	AJ	"PERFORMANCE OF A 576x576 OPTICAL CROSS CONNECT," Laor, et al. NFOEC, Chicago, Illinois, pages 1-5. September 26, 1999.						
NO Date SA	AK	"Control and shape design of an electrically-damped comb drive for digital switches," Yijian Chen. Proceedings of SPIE Vol. 4178, 2000. Pages 387-394.						

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U.S. PTO
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							Translation
		Document Number	Date	Country	Class	Subclass	Yes No
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SA	AN	"THE RISE OF OPTICAL SWITCHING," David J. Bishop et al. Scientific American, pages 88-94. January 2001.					
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NO Date	AQ	"MEMS Feedback Control Using Through-Wafer Optical Device Monitoring," J.M. Dawson, et al. Proceedings of SPIE Vol. 4178, 2000. Pages 221-227.					
SA	AR	"A FLAT HIGH-FREQUENCY SCANNING MICROMIRROR," Robert A. Conant, et al. 2000 Solid-State Sensor & Act Workshop, Hilton Head, S.C., June 4-8, 2000.					
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NO Date SA	AT	"MEMS actuators for silicon micro-optical elements," Norman C. Tien and Daniel T. McCormick. Proceedings of SPIE Vol. 4178, 2000. 256-267.					
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SA	AW	"Lightweight, Optically Flat Micromirrors for Fast Beam Steering," Jocelyn T. Nee, et al. Presented at IEEE/LEOS Optical MEMS 2000 Conference, August 21-4, 2000, Kauai, Hawaii, USA. 2 pages.					
SA	AX	"Optical MEMS for Optical Communications - Trends and Developments," Veljko Milanovic. Adriatic Research Institute. Pages 2-6. Downloaded December 20, 2001.					
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	AZ						
	BA						
	BB						
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No date ↓	BE	Topical Review "The future of MEMS in telecommunications networks," James A. Walker. J. Micromech, Microeng 10(2000)R1-R7. Printed in the UK.
	BF	D.J. Bishop Presentation, "Silicon Micromachines for Lightwave Networks: Can Little Machines Make it Big?" Lucent Technologies, Bell Labs Innovations. 83 pages. Date unknown.
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SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Inventor: Vlad J. Novotny
"Deep-Well Lithography Process for Forming Micro-Electro-Mechanical Structures"	Group Art Unit: 2874
	Examiner Name: Unknown
	Attorney Docket No.: AO-001-2D

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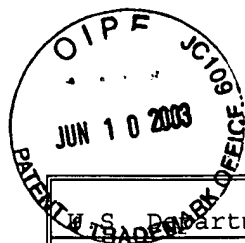
SA	AD	"Silicon micromachines for lightwave networks: the little machines that will make it big," by David Bishop. December 2000. SPIE's Optics & Information Systems. 8 pages.
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	C						
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	E						

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	F							

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SA	G	"Multi-Layer, Self-Aligned Vertical Combedrive Electrostatic Actuators and Fabrication Methods." Inventors: Behrang Behin and Satinderpall Pannu. Publication No.: US 2002/0005976 A1. Publication Date: January 17, 2002. Application No.: 09/810,333, filed March 14, 2001.
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	I	
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